



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM FORMATION, METHOD FOR
ELECTRODE FORMATION, AND APPARATUS FOR ELECTRODEPOSITED FILM
FORMATION

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the May 5, 2004 Office Action, Applicants respectfully request reconsideration and allowance of the above-identified patent application.

The courtesies extended to Applicants' representative by Examiner Wong at the interview held June 22, 2004, are appreciated. The reasons presented at the interview as warranting favorable action are incorporated into the remarks below and constitute Applicants' record of the interview.

Claims 30-37 are pending. Claims 30-37 are rejected under 35 U.S.C. §102 over Melcher et al. Applicants respectfully traverse the rejection.

Claim 30 is directed to an apparatus for electrodeposited film formation. The apparatus comprises an electrolyte solution bath holding: (a) an electrolyte solution containing ions to constitute an electrodeposited film and (b) an object to be treated of which at least the surface permits generation of charged particles when irradiated with a laser beam.

The apparatus also comprises a pulse laser outputting a laser beam whose pulse width is less than a picosecond and which irradiates at least part of the object to be treated positioned in the electrolyte solution.

Melcher teaches a device in which a cathode is placed in an electrolyte solution.

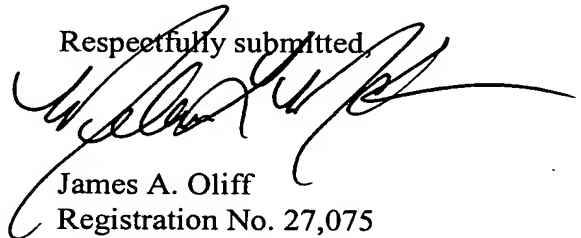
Col. 2, lines 50-51. An energy source is focused on the regions of the surface of the cathode where the energy is absorbed, causing localized heating. Col. 2, lines 57-59. The energy source may be a light source. The light beam emitted from the light source may be modulated by a modulator that may be placed between the light source and the lens system or alternatively between the lens system and the cathode. The modulator may be a mechanical light chopper when the modulation rate is low or an optical modulator can be employed when more rapid modulation is sought. Col. 4, lines 17-24.

Melcher does not teach an apparatus comprising a pulse laser. Instead, Melcher only discloses continuous lasers, such as argon lasers or krypton lasers, and makes a pulse beam by chopping that continuous laser beam mechanically. Thus, the apparatus of the present invention is clearly different than the apparatus described in Melcher.

In view of the foregoing, it is respectfully submitted that this application is in condition for allowance. Favorable reconsideration and prompt allowance of claims 30-37 are earnestly solicited.

Should the Examiner believe that anything further would be desirable in order to place this application in even better condition for allowance, the Examiner is invited to contact the undersigned at the telephone number set forth below.

Respectfully submitted,



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Date: June 25, 2004

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